ABSTRACT

A substrate support and method for reducing the migration of a conductive material is provided. In one embodiment, a support includes a chuck body having a support side and a backside. A guard electrode is disposed within the chuck body proximate the backside of the chuck body. In another aspect, a method for reducing the migration of a conductive material is provided. In one embodiment, the method includes the steps of disposing a guard electrode proximate a backside of the substrate support and applying a voltage to the guard electrode.

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